A NOVEL COATING HAVING REDUCED STRESS AND A METHOD OF DEPOSITING THE COATING ON A SUBSTRATE

ABSTRACT

A method of depositing a coating on a substrate, the method comprising the steps of: (a) depositing material on a substrate by performing a cathodic vacuum arc (CVA) deposition step; and (b) depositing material on a substrate by performing a physical vapor deposition (PVD) step that excludes CVA deposition wherein the thickness of the material deposited in step (a) is greater than the thickness of material deposited in step (b).

Fig. 1